



Application Serial No. 09/905,286
Filing Date July 13, 2001
Inventor Basceri et al.
Assignee Micron Technology, Inc.
Group Art Unit 1762
Examiner E. Fuller
Attorney's Docket No. MI22-1724
Title: Chemical Vapor Deposition Methods of Forming Barium Strontium Titanate
Comprising Dielectric Layers

INFORMATION DISCLOSURE STATEMENT

To: Mail Stop RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

From: Jennifer J. Taylor, Ph.D.
(Tel. 509-624-4276; Fax 509-838-3424)
Wells St. John P.S.
601 W. First Avenue, Suite 1300
Spokane, WA 99201-3828

Dear Sir:

The Examiner's attention is directed to the references which are listed on
the attached Form PTO-1449 and copies of which are attached.

Citation of these references is respectfully requested.

Respectfully submitted,

Dated: July 9, 2004

By: Jennifer J. Taylor
Jennifer J. Taylor
Reg. No. 48,711

Form PTO-1449

U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICEATTY. DOCKET NO.
MI22-1724SERIAL NO.
09/905,286LIST OF ART CITED BY APPLICANT
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July 13, 2001GROUP
1762

U.S. PATENT DOCUMENTS

*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA 4,261,698	04/81	Carr et al.			
	AB 4,691,662	09/87	Roppel et al.			
	AC 5,261,961	11/93	Takasu et al.			
	AD 5,270,241	12/93	Dennison et al.			
	AE 5,312,783	05/94	Takasaki et al.			
	AF 5,392,189	02/95	Fazan et al.			
	AG 5,395,771	03/95	Nakato			
	AH 5,468,687	11/95	Carl et al.			
	AI 5,525,156	06/96	Manada et al.			
	AJ 5,614,018	03/97	Azuma et al.			
	AK 5,656,329	08/97	Hampden-Smith			
	AL 5,663,089	09/97	Tomozawa et al.			

FOREIGN PATENT DOCUMENTS

	Document Number	Date	Country	Class	Subclass	Translation	
						Yes	No
	AM EP 0 030 798	06/81	EPO				
	AN GB 2 194 555 A	03/88	United Kingdom				
	AO EP 0 306 069 A2	03/89	EPO				
	AP EP 0 388 957 A2	09/90	EPO				
	AQ JP2250970	10/90	Japan				

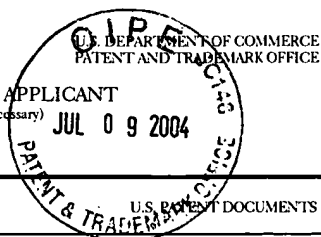
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

	AR		Aoyama et al., <i>Leakage Current Mechanism of Amorphous and Polycrystalline Ta₂O₅ Films Grown by</i>
			<i>Chemical Vapor Deposition</i> , 143 J. ELECTROCHEM SOC., No. 3, pp 977-983 (March 1996).
	AS		Stemmer et al., <i>Accommodation of nonstoichiometry in (100) fiber-textured (Ba_xSr_{1-x})Ti_{1+y}O_{3+z} thin films grown</i>
			<i>by chemical vapor deposition</i> , 74 APPL. PHYS. LETT., No. 17, pp. 2432-2434 (26 April 1999).
	AT		Streiffer et al., <i>Ferroelectricity in thin films: The dielectric response of fiber-textured (Ba_xSr_{1-x})Ti_{1+y}O_{3+z} thin</i>
			<i>films grown by chemical vapor deposition</i> , 86 J. APPL. PHYS. No. 8, pp. 4565-4575 (15 October 1999).
EXAMINER			DATE CONSIDERED

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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ATTY. DOCKET NO.
M122-1724

SERIAL NO.
09/905,286

APPLICANT
Cem Basceri et al.

FILING DATE
July 13, 2001

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1762

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	AA	5,702,562	12/97	Wakahara			
	AB	5,719,417	02/98	Roeder et al.			
	AC	5,723,361	03/98	Azuma et al.			
	AD	5,736,759	04/98	Haushalter			
	AE	5,976,990	11/99	Mercaldi et al.			
	AF	5,989,927	11/99	Yamonobe			
	AG	6,101,085	08/00	Kawahara et al.			
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	AK	6,325,017 B1	12/01	DeBoer et al.			
	AL	6,335,049 B1	01/02	Basceri			

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	AM	04-24922	01/92	Japan				
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	AO	04-180566	06/92	Japan				
	AP	08-060347	03/96	Japan				
	AQ	EP 0 810 666 A1	12/97	EPO				

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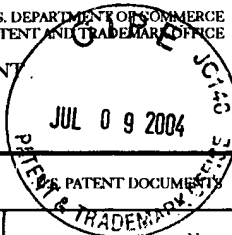
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*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	6,566,147 B2	05/03	Basceri et al.			
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							Yes	No
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	AN	JP2000091333	03/00	Japan				
	AO	WO 01/16395	03/01	WIPO				
	AP							
	AQ							

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

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